

Microstructural characterization of advanced superconducting materials for different components of the CERN Future Circular Collider (FCC-hh)

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The Microstructure Analysis



"Seeing is believing"

Manfred Von Heimendahl in his introduction to Electron Microscopy of Materials, 1980



Mikros (small) Skopeo (look at) Greek Origin





The Microstructure Analysis



De Broglie (1924): $\lambda = h / p$		e t t t t t t t t t t t t t t t t t t t
2.5 pm @ 200 kV	LIGHT MICROSCOPE	ELECTRON MICROSCOPE
Source of illumination	The ambient light source is light for the microscope	Electrons are used to "see" – light is replaced by an electron gun built into the column
Lens type	Glass lenses	Electromagnetic lenses
Magnification method	Magnification is changed by moving the lens	Focal length is charged by changing the current through the lens coil
Viewing the sample	Ocular	Fluorescent screen or digital camera
Use of vacuum	No vacuum	Entire electron path from gun to camera must be under vacuum





The Microstructure Analysis





"We see past time in a telescope and present time in a microscope. Hence the apparent enormities of the present" Victor Hugo, Victor Hugo's Intellectual Autobiography: (Postscriptum de ma vie) (1907)

	TEM	SEM
Electron Beam	Broad, static beams	Beam focused to fine point; sample is scanned line by line
Voltages Needed	TEM voltage ranges from 60-300,000 volts	Accelerating voltage much lower; not necessary to penetrate the specimen
Interaction of the beam electrons	Specimen must be very thin	Wide range of specimens allowed
Imaging	Electrons must pass through and be transmitted by the specimen	Information needed is collected near the surface of the specimen
Image Rendering	Transmitted electrons are collectively focused by the objective lens and magnified to create a real image	Beam is scanned along the surface of the sample to build up the image





Transmission electron microscopy



Sample preparation



Focused Ion Beam - FIB



TEM - scheme



<u>USIEM</u>



Scanning electron microscopy



Sample preparation

SEM - scheme







USIEM



Electron – Matter Interaction





Towards the CERN Future Circular Collider



M



High-field superconducting bending magnets: Nb₃Sn Critical current density J_c = 1.5 kA/mm² at 16 T & 4.2 K



- Low surface resistance beam screen: T1223 Operation T = 50 K
- Superconducting links: MgB₂





USIEM











SEM imaging: SE vs BSE







USIEM







<u>USIEM</u>





Silicon Drift





Spectrum: I (counts) vs E (eV)





Process time, Resolution and Dead time









SIGM

\succ SEM-EDX line scans over different sub-elements along the radial direction ightarrow Sn gradient statistical analysis









Internal Tin (IT) wire overview







Manufacturing process

Internal Tin (IT) wire overview









USIEM







17 MYISO





\succ SEM-EDX line scans over different sub-elements along the radial direction \rightarrow Sn gradient statistical analysis



Sub-elements radial direction



Gradient: (0.015 ± 0.004) at. %/μm







SIEM

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Cluster layout

Scanning Hall Probe Microscopy (SHPM) – local transport measurements



TI1223 thin films from CNR SPIN (Genoa-Italy)



Ag

TI1223

TI1212

SIEM

- Ag Precursor film + Tl₂O₃ powder in a gold capsule
- Heat treatment: 885 °C/ 10 min



Sr rich

Ca rich

- Plate-like grains
- Large grains \rightarrow 200 μ m
- Tl1212 more than Tl1223





By changing the powder quantity during the thallination process...



Substrate: Ag

TI1212 🗸

A Leveratto et al 2020 Supercond. Sci. Technol. 33 054004



TI-





Better coverage obtained \checkmark



- Sample with big grains
- Ag substrate visible
- Not so good coverage

- Large number of plate-like grains
- Better coverage, substrate is less visible
- Better shape of 1223 grains









SIEM

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C sources: Hemoglobin, Inulin, C-soot...

С clusters **Bright Field TEM** images . Pinning (\bullet) 100 nm centres Grain boundary HRTEM – High C cluster Resolution **TEM** images









STEM EDX Map







Artificial Pinning Centres Nb₃Sn





STEM images

ZrO₂ particles (black spots)

// Hyper Tech Research, Inc.





- PP density
- PP size

Grain size evaluation

Electron Backscatter Diffraction – EBSD in transmission mode



Courtesy of S. Pfeiffer (TU Wien - USTEM)







Final remarks





Validation of innovative manufacturing processes









Help analyzing the pinning centres behavior









Thank you for the attention!

FCC



LHC

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